

IN THE SPECIFICATION

Please amend the Abstract as follows:

The present invention provide discloses a ceramic substrate for semiconductor manufacture and/or inspection which is conducive to decrease in  $\alpha$ -rays radiated  $\alpha$ -rays[.,] and change to minimize changes in of thermal conductivity with passage of the as a function of time, thereby yielding a and which is superior in the temperature controllability. This invention is related to a ceramic substrate for apparatuses for use in semiconductor manufacture and/or inspection, Wherein wherein the level of  $\alpha$ -rays radiated from said ceramic substrate exceeds  $0.25 \text{ c/cm}^2\cdot\text{hr}$  and is not higher than  $50 \text{ c/cm}^2\cdot\text{hr}$ .